# Application/Control No. 10/005,483 Examiner Shuwang Liu Applicant(s)/Patent Under Reexamination SNELL ET AL. Art Unit Page 1 of 1

## Notice of References Cited

#### **U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	Α	US-6,567,389	05-2003	Honkasalo et al.	370/342
	В	US-6,442,380	08-2002	Mohindra, Rishi	455/234.1
	С	US-6,404,732	06-2002	van Nee, D. J. Richard	370/209
	D	US-5,537,398	07-1996	Siwiak, Kazimierz	370/204
	Е	US-			
	F	US-			
	G	US-			
	н	US-			
	ı	US-			
	J	US-			
	К	US-			
	L	US-			
	М	US-			

#### **FOREIGN PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	0					
	Р					
	Q					
	R					
	S					
	Т					

### **NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)					
	U						
	٧						
	w						
	x						

\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).) Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.